

Gallium Oxide Nanostructures for High Temperature Sensors

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Outline

Introduction

Research Objectives

Experiments

Results

□Intrinsic Ga₂O₃ □Tungsten (W)-doped Ga₂O₃ Summary & Outlook



Introduction

Challenging Environment in Power Systems









Gallium Oxide (Ga₂O₃)







Project Objectives and Goals



<u>Objective 1</u>: To fabricate high-quality pure and doped Ga₂O₃-based materials and optimize conditions to produce unique architectures and morphology at the nano scale **<u>Objective 2</u>**: Derive the structure-property relationships at

the nanoscale dimensions and demonstrate hightemperature oxygen sensing (faster response) and stability

Objective 3: To promote research and education in the area of sensors and controls

<u>**Goal:**</u> Design the high temperature oxygen sensors (employing Ga_2O_3 -based nanostructures)

Project Work Plan







Experiments

Materials



 $\frac{\text{Target (for Deposition)}}{\text{Ga}_2\text{O}_3 \& \text{W}}$

- Substrate(s):
- Si(100)
- Alumina





Fabrication – Thin Films

- RF magnetron sputtering
- Deposition Conditions
 Fixed:
 - Base pressure ~10⁻⁶ Torr
 - Powers: $Ga_2O_3 \rightarrow 100 \text{ W}$
 - Target-Substrate distance: 7 cm
 - Sputtering gas: Argon + O₂

Variables:

Sample set 1 (Intrinsic):

Substrate Temperature: RT-500 °C

Sample set 2 (W-Doped):

Tungsten Target Power (50 to 100W)

Substrate Temperature = 500 °C



Sample set 3 (W-Doped):

Target Powers = const.; Substrate temperature varied from 500 to 800°C



Sensors and Sample Matrix



- Extremely thin (~50 nm) samples
- Two silver electrodes attached on the surface



- ~200 nm thick Ga-oxide
- 200 nm thick Pt interdigited electrodes
- Spacing:
 100 μm



- Bulk (ceramic pellets)
- Electrical Impedance

Sensor Performance - Electrical

- Oxygen introduced and partial pressures of oxygen were varied
- Evaluation at temperatures ≥ 700 °C



• Constant current



Crystal Structure



500 °C is favorable/critical to provide sufficient energy for Ga_2O_3 film crystallization (β phase)



L = $L_o \exp(-\Delta E/k_B T)$ L: Average size L_0 : Pre-exp. factor (film, substrate materials) ΔE : Activation energy, k_B : Boltzmann constant and T: Absolute temperature.

Morphology & Composition







Microstructure & Electronic Properties





Tungsten Doping

W-Doped Ga-Oxide

t = 200 nm

W-Power (Watts)	W-Content (Atomic %)
0	0
50	5
75	10
100	15

Crystal Structure – Power dependence







Band Gap (Power dependence)

E.J. Rubio and C.V. Ramana, Appl. Phys. Lett. 102, 191913 (2013).



Crystal Structure – (Temp. Dependent)





Only β -phase presented for all films.

Mechanical Characteristics





Hardness & Elastic Modulus increases with W-content



Can be tolerant and impact resistant

Oxygen Sensor Characteristics





Intrinsic Ga₂O₃ films Time response: 62 sec

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Oxygen Sensor Characteristics



W (5 at%) - doped Ga₂O₃ films 20% O, out 1800 15% Resistancs (Ohms) 10% 1680 1560 1440 O, in 1000 2000 3000 Time (seconds)

- Ga_2O_3 based films showed oxygen sensitivity at 700 °C,
- As an n-type semiconductor the resistance of the film increased in the presence of oxygen.
- Time response was drastically improved with the incorporation of tungsten



- Increasing W-content reduces sensitivity of the sensors
- Time response is increased with increasing W-content
- Stability of the electrical properties is reduced with increasing W-content

Two Probe Oxygen Sensor Characteristics



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Hot Gas Exposure (600-700 nm)



•W-doped Ga-oxide demonstrated sensing properties to oxygen at 700 °C.

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0.12

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Intensity vs. Gas Exposure Summary



- ♦ W-doped films showed being sensible to H₂ and O₂.
- O_2 sensitivity increased from 10% to 15% of O_2 into Ar, but decrease again at 20%
- Sensitivity to gases was optimum in Ar environment, but small-to-non response in a mixture of Ar+Air

Electrical Impedance Analyses



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Crystal Structure – (after annealing)





Deposition Temperature Ts=500 °C; Annealing Temperature Ta=700 °C for 30 min

Heat Treatment



- β-phase is stable for all films after annealing
- surface morphology suffer porous formation for Wdoped films.
 Evidence of Wself diffusion



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How does it work?



Impact

Journal Publications:

- 1. E.J. Rubio and C.V. Ramana, Appl. Phys. Lett. **102**, 191913 (2013).
- 2. A.K. Narayana Swamy, E. Shafirovich, and C.V. Ramana, Ceram. Inter. **39**, 7223 (2013).
- S.K. Samala, E.J. Rubio, M. Noor-A-Alam, G. Martinez, S. Manandhar, V. Shutthanandan, S. Thevuthasan, and C.V. Ramana, J. Phys. Chem. C 117, 4194 (2013).
- 4. Two others (under preparation)

Conference Presentations:

- 1. International Materials Research Congress (IMRC) to be presented (2015)
- 2. Southwest Energy Symposium, 2015, El Paso, TX
- 3. TMS 2014; ICMCTF 2015
- 4. ICMCTF-2013, San Diego, CA
- 5. AVS International Symposium, 2012
- 6. Southwest Energy Symposium, March 24, 2012, El Paso, TX

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Education & Training:

- 1. Ernesto J. Rubio: PhD (Full)
- 2. A.K. Narayana Swamy: PhD (part of disseration)
- 3. Sampath K. Samala: MS (thesis)
- 4. Abhilash Kongu: MS (non-thesis)



Summary and Conclusions

- Optimum conditions were established to fabricate Ga_2O_3 and W-doped Ga_2O_3 with the stable β -phase (monoclinic)
- Intrinsic Ga₂O₃ and W-doped Ga₂O₃ demonstrated to be sensitive to oxygen at high temperatures, with improved time of response for W-incorporation

Future Work













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THANK YOU!

